

CLAIMS:

1. A probe station comprising:
 - (a) a platen suitable for supporting a probe for testing a device under test;
 - (b) a support suitable for supporting said device under test thereon;
 - (c) a conductive member
- 5 2. The probe station of claim 1 wherein at least 80% of the top surface of said second platen terminating in free space when said optical probe is not supported thereon.
- 10 3. The probe station of claim 1 wherein at least 80% of the top surface of said second platen terminating in free space when said optical probe is not supported thereon.
- 15 4. The probe station of claim 1 wherein at least 85% of the top surface of said second platen terminating in free space when said optical probe is not supported thereon.
- 20 5. The probe station of claim 1 wherein at least 90% of the top surface of said second platen terminating in free space when said optical probe is not supported thereon.

6. The probe station of claim 1 wherein at least 95% of the top surface of said second platen terminating in free space when said optical probe is not supported thereon.
7. The probe station of claim 1 wherein said second platen has a greater top surface area than said first platen.
8. The probe station of claim 1 wherein said second platen has a smaller top surface area than said first platen.
8. The probe station of claim 1 wherein said second platen has the same surface area as said first platen.
10. The probe station of claim 1 wherein said first platen is maintained in position with respect to said second platen by gravity such that if said probe station were turned upside down said first platen would freely fall away from said second platen.